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Please use this identifier to cite or link to this item: http://hdl.handle.net/123456789/2212	
Title:	High-fidelity large area nano-patterning of silicon with femtosecond light sheet
Authors:	Sidhu, M.S. (/jspui/browse?type=author&value=Sidhu%2C+M.S.)
	Munjal, P. (/jspui/browse?type=author&value=Munjal%2C+P.)
	Singh, K.P. (/jspui/browse?type=author&value=Singh%2C+K.P.)
Keywords:	Ultrashort Laser Pulses
	Nanostructures
	Electron microscopy images
	Nano Patterning
Issue Date:	2018
Publisher:	Springer-Verlag
Citation:	Applied Physics A: Materials Science and Processing, 124(1)
Abstract:	We employ a femtosecond light sheet generated by a cylindrical lens to rapidly produce high-
	fidelity nano-structures over large area on silicon surface. The Fourier analysis of electron
	microscopy images of the laser-induced surface structures reveals sharp peaks indicating good
	homogeneity. We observed an emergence of second-order spatial periodicity on increasing the
	scan speed. Our reliable approach may rapidly nano-pattern curved solid surfaces and tiny
	objects for diverse potential applications in optical devices, structural coloring, plasmonic
	substrates and in high-harmonic generation
URI:	https://link.springer.com/article/10.1007/s00339-017-1459-3
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